



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Fukashi HARADA et al.**

Group Art Unit: **2811**

Serial No.: **10/649,746**

Examiner: **Ori NADAV**

Filed: **August 28, 2003**

Confirmation No.: **5719**

For: **MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE
INCLUDING AN ANISOTROPIC ETCHING STEP (As herein amended)**

Attorney Docket Number: **031071**
Customer Number: **38834**

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

September 3, 2004

Sir:

In response to the Office Action dated May 3, 2004, the response date of which having been extended by one month to September 3, 2004, Applicants amend the claims as follows and submit the following remarks.

Amendment to the Title is indicated on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims that begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.

Response under 37 C.F.R. §1.111

Attorney Docket No. 031071

Serial No. 10/649,746

Amendments to the Title:

Please amend the title of the invention as follows:

“Manufacturing Method of Semiconductor Device Including an Anisotropic Etching Step”.